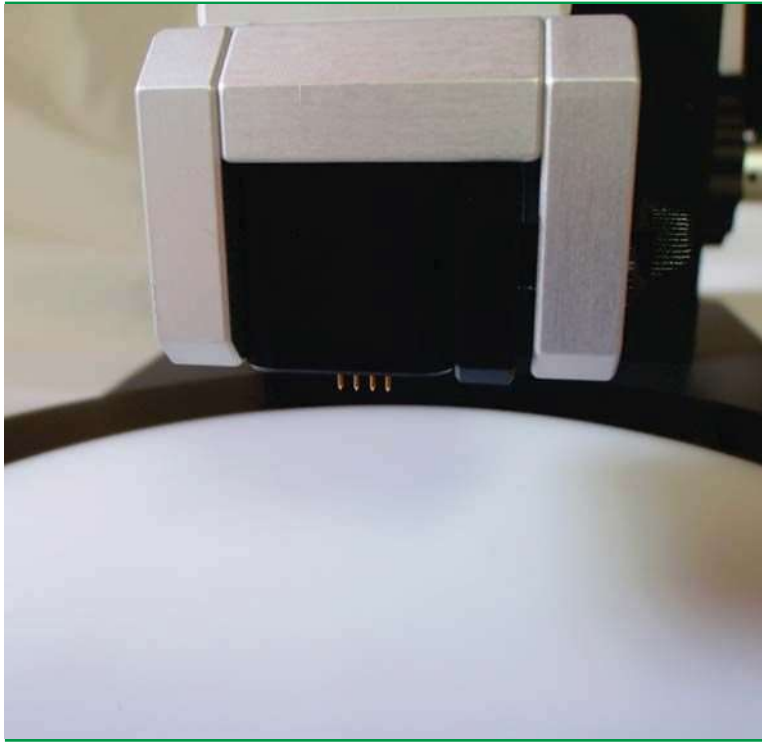


Your Partner in Probing Solutions



Four Point Probes and Probe Stand

For Testing Yield Of All Your
Thin-Film Samples

Everbeing offers the four point probe stand you need to perform your sheet resistance and resistivity measurements. All probe stands uses a linear formation of spring probe tips which are connected via banana cables to a DMM or SMU. The stands vary in features slightly.

Probes

- Four spring probes made of BeCu 1600 μm spaced apart. Each probe has 42 g force.
- Our probes can be customized for different spacing and optional Tungsten material
- Individual spring probes allows contact with uneven substrates

Ease of Use

- Our probe levers reliable and accurate to use. Fine Z-Motion Adjustment Model Optional
- Ready to go when connected to a meter

For Wafers and Other Thin Films Semiconductors

- Ideal for testing yield of fabrication recipe
- Large chuck allows for wafers and other films/glass samples for measuring

FOUR POINT PROBE

Station Models



SR-4

The SR-4 is our standard four point probe stand featuring a durable base with lever actuated probing with an up and down position. Since the probes are spring actuated, we've added the adjustment knob at the top side to fine adjustment contact depth according to your device.

Dimensions (in mm): 250 x 480 x 220 (W x D x H)

Weight: 12 kg

Wafer Carrier Size: 6" (150 mm)

Z-Motion Resolution: 1 μ m



KSR-4

The KSR-4 is our economical four point probe stand featuring a larger base with lever actuated probing. This lever holds its spot at all range of motion and allows users to probe to desired depth.

Dimensions (in mm): 350 x 350 x 180 (W x D x H)

Weight: 5 kg

Wafer Carrier Size: 6" (150 mm)

Lever Resolution 30 μ m



R-2

The R-2 is our smallest four point probe stand featuring a spring-loaded probe arm. As the arm is pressed down, the probe will be in contact with the sample allowing for quick measurements to the SMU. The arm will raise as the knob is released.

Dimensions (in mm): 80 x 150 x 150 (W x D x H)

Weight: 1 kg

Wafer Carrier Size: 2" (50 mm)

Z-Press Resolution 1000 μ m

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Common Specifications

Electrical Connections	4x Banana Female
Wafer Carrier Material	Teflon
Probe Head Size	15 mm W x 35 mm D x 20 mm H
Probe Pitch	1600 μm (62.5 mil)
Probe Material	BeCu
Probe Pin Diameter	100 μm
Probe Head Connection	Custom 4-Pin Connection

Alternate Probe Specifications

Probe Head Size	15 mm W x 35 mm D x 20 mm H
Probe Pitch	1000 μm (40 mil)
Probe Material	Tungsten Carbide
Probe Pin Diameter	40 μm
Probe Head Connection	Custom 4-Pin Connection

Optional Accessories (Chuck Stage)

Applicable Models	SR-4, KSR-4
Chuck Travel Range	6" x 6" (X and Y)
Chuck Quick Resolution	25 mm/rev
Coaxial Chuck Movement	Bevelled Gear and Rack 0.8mm Pitch

Optional Accessories (Hot Chuck Stage)

Applicable Models	SR-4, KSR-4
Chuck Size	4" (100 mm)
Temperature Range	RT to 200° C
Temperature Resolution	0.5° C
Heating Type Resolution	Resistive

FOUR POINT PROBE


Short Gallery



SR-4 equipped with chuck stage and hot chuck



R-2 paired with Keithley 2450 SMU

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